Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	6	embroidery and design and rule and knowledge and base	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2004/04/29 11:56
L2	1	L1 and @ad<"20010223"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2004/04/29 11:38
L3	7	embroidery and rule and knowledge and base	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR manufacture Accept	OFF	2004/04/29 11:37
L4	2	L3 and @ad<"20010223"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2004/04/29 11:40
L5	3961	"needle point"	US-PGPUB; USPAT;	OR	OFF	2004/04/29 11:39
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L6	5	5 and knowledge and base and rule	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2004/04/29 11:40
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L8	549	706/47	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2004/04/29 11:49
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L10	45	sewing and design and rule and knowledge and base	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2004/04/29 12:00

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L14	585	706/46	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2004/04/29 12:05
L15	512	L14 and @ad<"20010223"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF .	2004/04/29 12:11
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L17	294	L16 and @ad<"20010223"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2004/04/29 12:11
S35	6.	embroidery and design and rule and knowledge and base	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2004/04/29 06:55
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